

REMARKS

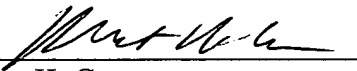
The amendment to paragraph 0027 corrects the abbreviations for chemical vapor deposition and atomic layer deposition and a typographical error in the word "deposition;" these corrections are immediately recognizable from the terms preceding the incorrect abbreviations. Applicants have not added new matter by this amendment.

If it is determined that a telephone conference would expedite the prosecution of this application, the Examiner is invited to telephone the undersigned at the number given below.

In the event the U.S. Patent and Trademark Office determines that an extension and/or other relief is required, applicant petitions for any required relief including extensions of time and authorizes the Commissioner to charge the cost of such petitions and/or other fees due in connection with the filing of this document to Deposit Account No. 03-1952 referencing docket no. 577182000100. However, the Commissioner is not authorized to charge the cost of the issue fee to the Deposit Account.

Dated: September 17, 2004

Respectfully submitted,

By 
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